2879

In re Application of:

TOSHIKAZU ONISHI ET AL.

Docket No. 03500.013314.2

Application No.: 10/014,131

Examiner: M. Santiago

Filed: December 13, 2001

Group Art Unit: 2879

For: METHOD FOR MANUFACTURING ELECTRON

EMISSION ELEMENT, ELECTRON SOURCE,

AND IMAGE FORMING APPARATUS

Date: May 24, 2005

THE COMMISSIONER FOR PATENTS P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Transmitted herewith is an Amendment in the above-identified application.

X No additional fee is required.

The fee has been calculated as shown below

CLAIMS AS AMENDED							
	(2) CLAIMS REMAINING AFTER AMENDMENT		(4) HIGHEST NO. PREVIOUSLY PAID FOR	(5) PRESENT EXTRA	RATE	ADDITIONAL FEE	
TOTAL CLAIMS	* 8	MINUS	**	0	x \$25 \$50	0	
INDEP. CLAIMS	* 5	MINUS	*** 6	0	x \$100 \$200	0	
Fee for Mu	0						
	0						

* If the entry in Column 2 is less than the entry in Column 4, write "0" in Column 5.

** If the "Highest Number Previously Paid For" IN THIS SPACE is less than 20, write "20" in this space.

*** If the "Highest Number Previously Paid For" IN THIS SPACE is less than 3, write "3" in this space.

	Verified Statement claiming small entity status is enclosed, if not filed previously.					
	A check in the amount of \$ is enclosed.					
	Charge \$ to Deposit Account No. 06-1205. A duplicate copy of this sheet is enclosed.					
X	Any prior general authorization to charge an issue fee under 37 C.F.R. 1.18 to Deposit Account No. 06-1205 is hereby revoked. The Commissioner is hereby authorized to charge any additional fees under 37 C.F.R. 1.16 and 1.17 which may be required during the entire pendency of this application, or to credit any overpayment, to Deposit Account No. 06-1205. A duplicate copy of this paper is enclosed.					
	A check in the amount of \$ to cover the fee for a month extension is enclosed.					
	A check in the amount of \$ to cover the Information Disclosure Statement fee is enclosed.					
X	Applicants' undersigned attorney may be reached in our New York office by telephone at (212) 218-2100. All correspondence should continue to be directed to our address given below.					
	Respectfully submitted					

Frank A. DeLucia Attorney for Applicants Registration No.: 42,476

FITZPATRICK, CELLA, HARPER & SCINTO 30 Rockefeller Plaza New York, New York 10112-3800 Facsimile: (212) 218-2200

NY_MAIN 502938v1



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re	Application of:) : Examiner: M. Santiago	,
TOS	HIKAZU ONISHI ET AL.)	
		: Group Art Unit: 2879	
Appl	lication No.: 10/014,131)	
Filed	l: December 13, 2001	;)	
TITCU	1. December 13, 2001	;	
For:	METHOD FOR MANUFACTURING)	
	ELECTRON EMISSION ELEMENT,	:	
	ELECTRON SOURCE, AND IMAGE)	
	FORMING APPARATUS	: May 24, 2005	
Com P.O.	Stop Amendment missioner for Patents Box 1450 andria, VA 22313-1450		
	AMENI	<u>OMENT</u>	
Sir:			
	In response to the Office Actio	n of February 24, 2005, please	amend the
abov	e identified application as follows:		
		I hereby certify that this correspondent United States Postal Service as firs addressed to: Commissioner for Patents VA 22313-1450 on FRANK A. DeLUCIA (R) Chame of Attorney for	t-class mail in an envelope s, P.O. Box 1450, Alexandria, May 24, 2005 (Date of Deposit) EG. NO. 42,476)
		Man /	May 24, 2005
		Signature	Date of Signature